

PROGRAM SEMINARIUM

Inżynieria Powłok w Skali Nano – Rozwiązania dla Nowoczesnej Elektroniki

Monday 04.12.2017

| <i>Time</i> | Topic | Lecturer | Institution |
|----------------------|---|--|-------------------------------|
| 8:30 – 09:15 | Registration | .. | .. |
| 9:15 – 9:30 | Inauguration | Miłosz Czajkowski Tomasz Szablewski Prof. Marek Godlewski Prof. Roman Puźniak | TECHNOLUTIONS , IF PAN |
| 9:30 – 10:00 | Wide band gap oxides by Atomic layer Deposition – from applications in electronics to biology and medicine | Marek Godlewski | INSTYTUT FIZYKI PAN |
| 10:00 – 10:30 | Sample pre-treatment and laboratory methods of thin film deposition | Tomasz Szablewski | TECHNOLUTIONS |
| 10:30 – 11:20 | ALD principles, features and benefits | Mikko Suderlund | BENEQ OY |
| 11:20 – 11:45 | Coffee Break | | |
| 11:45 – 12:10 | ALD: Novel processes, plasma treatments | Harm Knoops | OXFORD INSTRUMENTS |

Technolutions

Miłosz Czajkowski
 ul. Jana Pawła II 52/56
 99-400 Łowicz

tel: +48 606 440 718
 fax: + 48 46 811 21 41
 NIP: 834-175-65-71
 kontakt@technolutions.pl

| | | | |
|---------------|---|-------------------------|---------------------------------|
| 12:10 – 12:40 | Moorfield PVD systems–application–focussed design | Jon Edgeworth | MOORFIELD NANOTECHNOLOGY |
| 12:40 – 13:05 | Plasma Enhanced Chemical Vapour Deposition. CCP vs ICP PECVD | Andreas Stamm | OXFORD INSTRUMENTS |
| 13:05 – 13:30 | ALD on and of 2D MATERIALS | Harm Knoops | OXFORD INSTRUMENTS |
| 13:30 – 14:30 | Lunch | | |
| 14:30 – 15:20 | ALD applications and case examples – LED, OLED, Sensors, displays, photovoltaics | Mikko Suderlund | BENEQ OY |
| 15:20 – 15:50 | nanoCVD and nanoETCH: A perfect partnership for graphene R&D | Jon Edgeworth | MOORFIELD NANOTECHNOLOGY |
| 15:50 – 16:30 | Surface treatment by Ion implantation | Christian Spoerl | IDONUS SARL |
| 16:30 – 18:00 | Coffee Break and Poster session | .. | .. |
| 19:00 – 22:30 | Dinner | | |

Tuesday 05.12.2017

| Time | Topic | Lecturer | Institution |
|---------------|---|------------------------------------|--|
| 9:00 - 09:40 | Enhanced Variable Shaped Beam Patterning for Micro- and Nanotechnology Applications | Hartmut Schacke | VISTEC |
| 9:40 - 10:20 | Direct writing laser lithography relating semiconductors, micro-mechanics and optics applications | Sven Preuss | HEIDELBERG INSTRUMENTS MIKROTECHNIK GmbH |
| 10:20 - 11:00 | Controlled etching at very low rates and Atomic Layer Etching for Nanoscale application | Andreas Stamm | OXFORD INSTRUMENTS |
| 11:00 - 11:20 | Coffee Break | | |
| 11:20 - 12:00 | Electrical metrologies in semiconductor area | Christophe Defranoux | SEMILAB |
| 12:00 - 12:40 | 3D optical surface metrology | Giancarlo Parma | LEICA |
| 12:40 - 13:00 | Modern methods in sample preparation and chemical imaging- nano IR/Raman/VIS using one AFM | Konrad Szczecina Marcin Lamczyk | PIK INSTRUMENTS |
| 13:00- 13:30 | Scanning electron microscopy in microelectronics characterisation | Marcel Laros | PHENOM WORLD |
| 13:30 - 14:20 | Lunch | | |
| 14:20 - 15:00 | Optical metrology solutions: 3D surface profilometry and film thickness analysis | Bernhard Botters | FILMETRICS |

Technolutions

 Miłosz Czajkowski
 ul. Jana Pawła II 52/56
 99-400 Łowicz

 tel: +48 606 440 718
 fax: + 48 46 811 21 41
 NIP: 834-175-65-71
 kontakt@technolutions.pl

| | | | |
|---------------|--|---------------------------------------|---------------|
| 15:00 - 15:40 | Spectroscopic ellipsometry in semi-conductor characterisation | Christohe Defranoux | SEMILAB |
| 15:40 - 16:05 | Super-resolution optical imaging of nanostructures using SMAL (Super-resolution Microsphere Amplifying Lens) | Gerardas Dambrauskas | LIG NANOWISE |
| 16:05 - 16:35 | Protochips™ in situ Electron Microscopy Solutions: Capabilities and Applications | Remy Berthier. | CEA Grenoble |
| 16:35 - 17:00 | The innovative robotic solutions for positioning, handling and electrical sensing at micro and nano scales | Karl Boche | IMINA |
| 17:00 - 17:20 | The End / Certificates | Miłosz Czajowski Tomasz Szablewski | TECHNOLUTIONS |

Technolutions

Miłosz Czajkowski
ul. Jana Pawła II 52/56
99-400 Łowicz

tel: +48 606 440 718
fax: + 48 46 811 21 41
NIP: 834-175-65-71
kontakt@technolutions.pl